



■. Issue Item Summary

NO	Module Name	Status		Remark
General Configuration		Available	None	
1	Process	ALD NIT		
2	Wafer Size	300mm		
3	Process Wafer Qty	100		
4	Process Type	NIT		
5	I/O Port / Smif	FOUP		
6	Load Lock	Yes		
7	Carrier Slot	25 Slot		
8	boat type	Dual		
System Control		Available	None	
1	System Controller	WAVES		
2	Operation Screen	Touch Screen		
3	Gas Flow Chart (Front & Rear)	◎	◎	
4	Temperature Controller			
5	Vacuum Pressure Control	CKD VEC		
6	Controller Transformer	1Φ 208V		
7	Heater Transformer	3Φ 480V		
8	Oxygen Analyzer	Yes		
9	HEC Pyro Ctrl	N/A		

NO	Module Name	Status		Remark
Process Gasses		Available	None	
1	Process Gas 1	N2		
2	Process Gas 2	NH3		
3	Process Gas 3	SiH2Cl2		
4	Process Gas 4	HF		
5	Process Gas 5	F2		
6	Process Gas 6	----		
7	Process Gas 7	----		
Gas Distrubution System		Available	None	
1	Basic Style	Conventinal		
2	Tubing Matrial	SUS-316L		
3	Tubing Finish	VCR		
4	Manual Valve	CKD		
5	Air-Operated Valve	CKD		
6	MFC			
Exhaust Distribution System		Available	None	

1	Air-Operated Valve Type	IGS Connect		
2	Main Valve	CKD VEC		
3	Cold Trap	◎		
4	Pump Line		◎	
Wafer/Cassette Handling		Available	None	
1	Wafer Alignment		◎	
2	Cassette Storage Qty	16		
3	Cassette In/Out Port	◎		
4	Cassette Handling Robot	◎		
5	Wafer Transfer Type	1 + 4		
6	Fork Material	AL2O3		
7	Fork Qty	5		
8	Fork Variable Pitch	◎		
9	Fork Wafer Presence Sensor	◎		
Elevator Handling		Available	None	
1	Boat Elevator	◎		
2	Auto Shutter	◎		
3	Boat Rotation	◎		
4	Mechanical Parts	◎		
Heating Chamber		Available	None	
1	Heater Type	VMM-56-302EX	+RCU	
2	T/C Type	None		
3	Spike T/C	None		